In re application of:

Serial No.:

Filled:

Chen et al

10/053,785

01/18/02 For:

'Method For Electroplating A Body-Centered Cubic Nickel-Iron

Hitachi Docket No. SJ0920000194US1

Alloy Thin Film With A High Saturation Flux Density'

COMMISSIONER FOR PATENTS ALEXANDRIA, VA 22313-1450

SIR:

Transmitted herewith for the above-identified application are:

- X Response to Office Action
- X Declaration and Power of Attorney for Patent Application
- X Statement of Added Inventor (37 CFR § 1.48(a)(1)
- X Written Consent of Assignee
- ___ No additional fee is required

The fee has been calculated as shown below:

CLAIMS REMAINING AFTER AMENDMENT	HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	<u>RATE</u>	ADDIT. FEE
TOTAL 14 MINU	JS 14	= 0	<u>x 50 = </u>	\$.00
INDEP. 1 MINU	JS 1	= 0	x 200 =	\$.00
FIRST PRESENTATI	ON OF MULTIPLE	DEP. CLAIM	+ 360 =	\$
			Surcharge	\$
			TOTAL	\$.00
Please charge my A duplicate copy	_		<u>587</u> in the am	ount of \$ <u>0.00</u>

- A duplicate copy of this sheet is attached.
- X The Commissioner is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account 50-2587 . A duplicate copy of this sheet is attached.

Any filing fees under 37 CFR 1.16 for the presentation of extra claims.

Any patent application processing fees under 37 CFR 1.17.

CERTIFICATE OF MAILING

I hereby certify that the above paper/fee is being deposited with the United States Postal Service as first class mail in an envelope addressed to the Commissioner for Patents, Alexandria, VA 22313-1450 on

January 14, 2005

Person Mailing paper/fee

<u>Shaina Yates</u>

Signature

Lewis L. Nunnelley Registration No. 42,942

Agent for Applicants Telephone (408) 717-6570

Hitachi Global Storage Technologies

Intellectual Property Law

Dept. NHGB/0142 5600 Cottle Road

San Jose, CA 95193